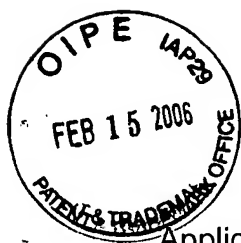


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PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No. 10/720,724
Filing Date: November 24, 2003
Applicant: Mitsuro ATOBE
Group Art Unit: 1763
Examiner: Rakesh K. Dhingra
Title: MASK VAPOR DEPOSITION METHOD, MASK VAPOR DEPOSITION SYSTEM, MASK, PROCESS FOR MANUFACTURING MASK, APPARATUS FOR MANUFACTURING DISPLAY PANEL, DISPLAY PANEL, AND ELECTRONIC DEVICE
Attorney Docket: 9319K-000606

Commissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

AMENDMENT

Sir:

In response to the Office Action mailed November 16, 2005, please amend the application as follows and consider the remarks set forth below.

Amendments to the Abstract begin on page 2 of this paper.

Amendments to the Claims begin on page 3 of this paper.

Amendments to the Drawings begin on page 5 of this paper.

Remarks begin on page 6 of this paper.